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Patent Docket No. 5649-1171

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Im et al.

Application No.: 10/747,803

Filed: December 29, 2003

For: *Methods and apparatus for depositing a thin film on a substrate*

Confirmation No.: 1856

Group Art Unit: 2827

December 8, 2004

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a Form PTO-1449 listing documents cited in a Korean Office Action for Korean Application Number 2002-0086874, which corresponds to the present application. Each document listed on the attached PTO-1449 was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Statement. A copy of any listed foreign patent document and/or non-patent literature including the Office Action is enclosed. An English language translation of the Korean Office Action and English language abstracts of the cited references are provided herewith.

No fee is believed due. However, the Commissioner is hereby authorized to charge any deficiency or credit any refund to Deposit Account No. 50-0220.

Respectfully submitted,

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I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on December 8, 2004.

Katie A. Chung

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.